

IPW



Docket No.: 4425-320

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Chien-Hsin LAI *et al.*

U.S. Patent Application No. 10/659,258

Filed: September 11, 2003

For: PLASMA APPARATUS AND METHOD CAPABLE OF ADAPTIVE IMPEDANCE
MATCHING

:
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: Confirmation No. 3535
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: Group Art Unit: 1763
:
: Examiner: Karla A Moore

RESPONSE TO NOTICE OF NON-COMPLIANT AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Notice of Non-Compliant Amendment mailed January 13, 2006, please
amend the above-identified application as follows: